IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	
· · · · · · · · · · · · · · · · · · ·	Examiner: J. G. Jelsma
Takako YAMAGUCHI et al.	
	Group Art Unit: 1795
Application No.: 10/529,891)	
	Confirmation No.: 7802
Completion of Entry into U.S. National	
Stage Under 35 U.S.C. § 371(c): July 26, 2005 :	
)	
For: EXPOSURE MASK, METHOD OF DESIGNING:	
AND MANUFACTURING THE SAME,)	
EXPOSURE METHOD AND APPARATUS, :	
PATTERN FORMING METHOD, AND DEVICE)	June 22, 2009
MANUFACTURING METHOD :	(Monday)

Mail Stop RCE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application as follows: